



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

ARTY.'S DOCKET: NREL/96-48

Applicant: Timothy A. Gessert)
Serial No.: 08/937,721) Group Art: 1741
Filing Date: September 25, 1997) Examiner: S. Mulpuri
Title: ION-BEAM TREATMENT TO)
PREPARE SURFACES OF)
P-CdTe FILMS)

PRELIMINARY AMENDMENT

Honorable Commissioner of Patents and Trademarks
Washington, D.C. 20231

Sir:

In advance of prosecution, and before this application is
taken up for examination on the merits, please amend the
application as follows:

IN THE CLAIMS

1. (Twice Amended) A dry process for making a low-resistance
electrical contact between a metal and a layer of polycrystalline
p-type CdTe surface by ion beam processing comprising:

a) placing a CdS/CdTe device having a polycrystalline
p-type CdTe into a chamber and evacuating said chamber to create
a vacuum;

b) orientating the polycrystalline p-CdTe side of the
CDs/CdTe device to face apparatus capable of generating Ar atoms

RECEIVED

NOV 04 1999

13
Pre Amend
C
Jareda
8.8.00

TO: 10/29/99
FROM: 10/29/99
SUB: 10/29/99